## Seiko Seiki STP-L451C **Technical Specifications**

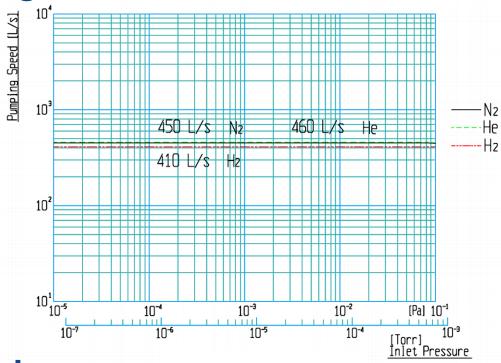
Pump Type			STP-L301	STP-L451	STP-L301C	STP-L451C
Corrosion resistant specific			N/A		Applicable	
Flange	Inlet port flange		VG100 ISO100 ICF152	VG150 ISO160 ICF203	VG100 ISO100 ICF152	VG150 ISO160 ICF203
size	Outlet port flange		KF25			
Purge port flange			N/A		KF10	
Pumping speed <sup>*1</sup> (L/s) N <sub>2</sub>		260	450	260	450	
(See chapter 7.1)		H <sub>2</sub>	290	410	290	410
Compression ratio*1 N <sub>2</sub> H <sub>2</sub>			> 108			
		2×10 <sup>4</sup>				
Ultimate pressure*1,*2 Pa		6.5×10 <sup>-6</sup> (5×10 <sup>-8</sup> Torr): VG/ISO 10 <sup>-8</sup> (10 <sup>-10</sup> Torr) order: ICF 10 <sup>-7</sup> (10 <sup>-9</sup> Torr) order: ICF				
		_	10° (10° To	rr) order: ICF	10°′ (10°° Tor	r) order: ICF
Allowable maximum Pa working pressure*1			6.7×10 <sup>-2</sup> (5×10 <sup>-4</sup> Torr)			
		D-			·	
Allowable maximum Pa backing pressure*1			13 (0.1 Torr)			
Enable exhaust gas			STP-L301/STP-L451 is not corrosion   Chlorine and Fluorine gases can be			
			resistant type. Chlorine and Fluor be used. Use corrosion resis type) when using ( Fluorine gases.	stant pump (C	used. When using contact Edwards.  The gas include but except "Li"  The gas include "Sn" and "In".  HBr	ing alkali metal,
Purge gas flow rate Pa·m³/s (SCCM)		_		1.7×10 <sup>-2</sup> (10)		
					(see chapter 2.2.2)	
Back pump size L/min		, ,				
Rated speed rpm		48,000 (Allowable speed range: between 25,000 and 48,000)				
Starting time min						
Stopping time min		5				
Vibration μm(0-P)		< 0.001 (at 48,000 rpm)				
Baking temperature °C		< 120				
Lubricating oil		Not necessary				
Installation position		Free				
Cooling method		Natural Air Cooling (Air cooling: for baking / gas suction)				
Mass		kg		14	13	14
Physical size Mm		(See chapter 6.3 Pump Overview Chart)				
Ambient air temp. range °C			0 to 40			
Storage temp. range °C			-25 to 55			
Commontio	on cable length	m		30 (ma	ximum)	

The data inside above table are the typical measured value. It's not guaranteed performance.

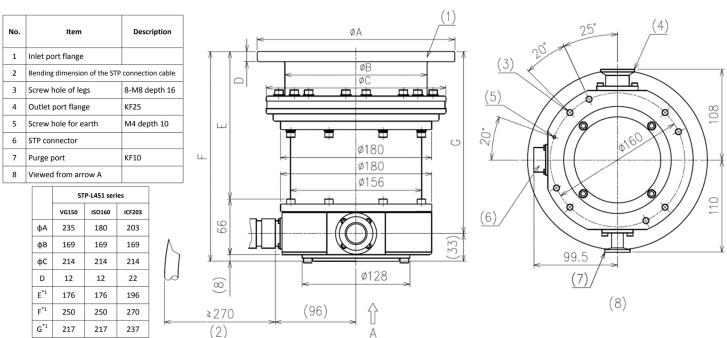
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# Seiko Seiki STP-L451C

### **Pumping Curves**



#### **Dimensions**



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## Seiko Seiki STP-L451C

#### **Features & Benefits**

- · designed to meet the low vibration requirements of advanced spectroscopy & microscopy tools
- vibration isolation system built into the pump body
- hydrocarbon-free pumping
- · minimal maintenance, low cost of ownership
- installation in any orientation
- full remote control interface
- suspended magnetic bearings eliminate contact between rotor & pump
- corrosion resistant model

### **Applications**

- plasma etch electron cyclotron resonance (ECR) etch film deposition CVD, PECVD, ECRCVD, MOCVD • sputtering • ion implantation source, beam line pumping end station · MBE · diffusion · photo resist stripping
- crystal/epitaxial growth
   wafer inspection
   load lock chambers
- · scientific instruments: surface analysis, mass spectrometry, electron microscopy · high energy physics: beam lines, accelerators